#### **Course Outline**

- Semiconductor Industry and Technology Overview
- IC Design Flows
- Timing in Digital Systems
- Front-end Design Flow
- Back-end Design Flow
- Interconnection and Signal Integrity
- Low-Power Design
- Design-for-Testability (DFT)

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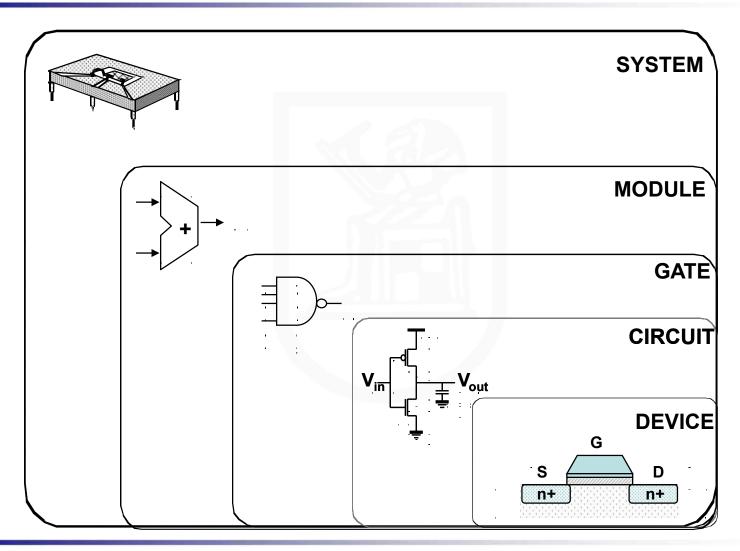
**Amr Wassal** 

### IC Design Flows

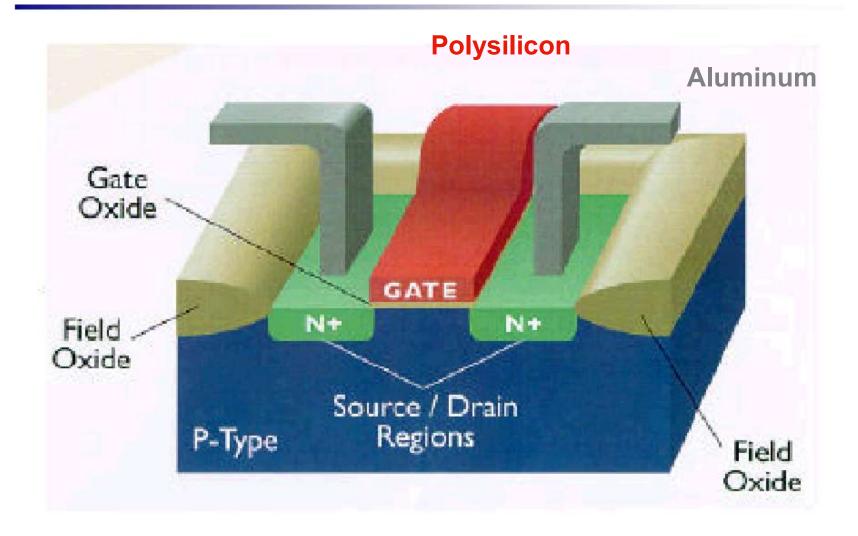


- The MOS Transistor
- Analog and Circuit Design
- Digital Logic Families
- Productivity Gap
- Digital Design Flows

## **Design Abstraction Levels**

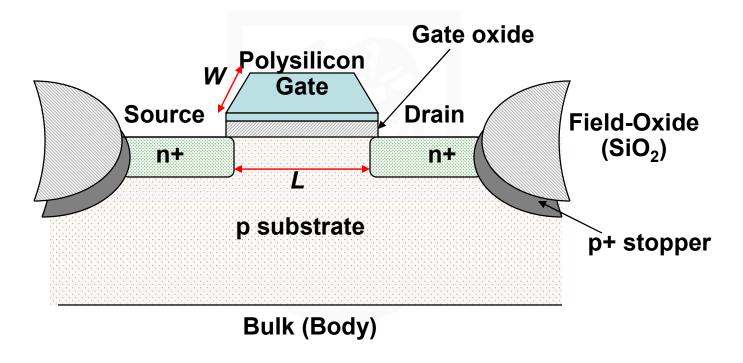


#### **The MOS Transistor**



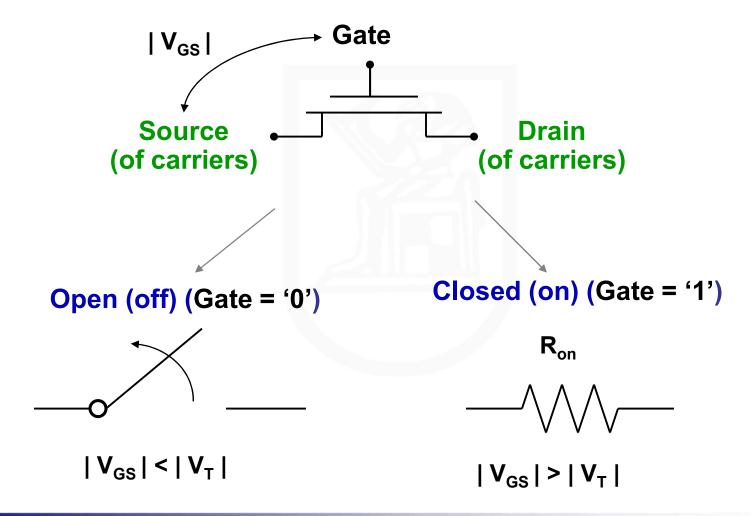
#### The NMOS Transistor Cross Section

n areas have been doped with donor ions (arsenic) of concentration  $N_{\text{D}}$  - electrons are the majority carriers

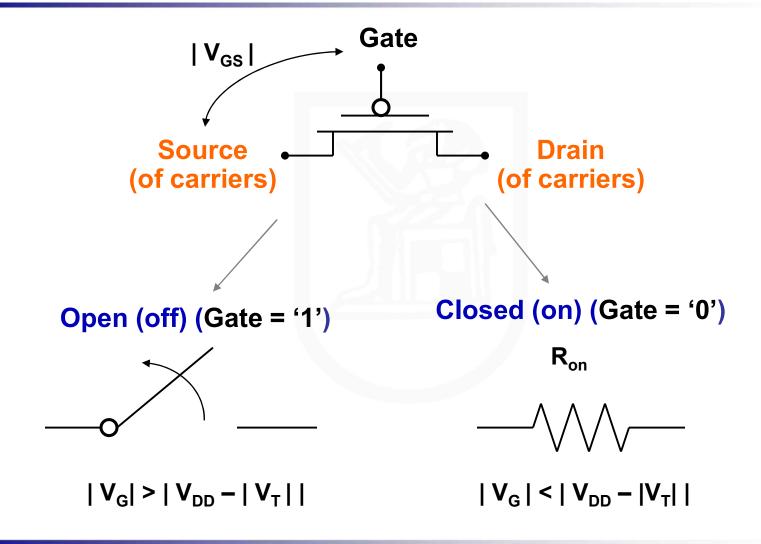


p areas have been doped with acceptor ions (boron) of concentration  $N_{\text{A}}$  -holes are the majority carriers

#### **Switch Model of NMOS Transistor**



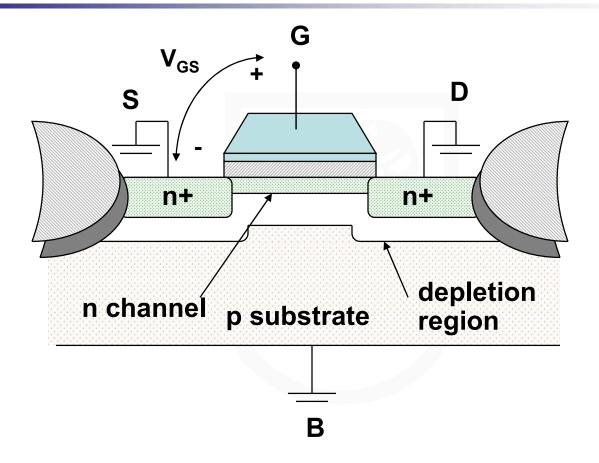
#### **Switch Model of PMOS Transistor**



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#### **Threshold Voltage Concept**



The value of  $V_{\text{GS}}$  where strong inversion occurs is called the threshold voltage,  $V_{\text{T}}$ 

## The Threshold Voltage

where

$$V_T = V_{T0} + \gamma(\sqrt{|-2\phi_F|} + V_{SB}| - \sqrt{|-2\phi_F|})$$

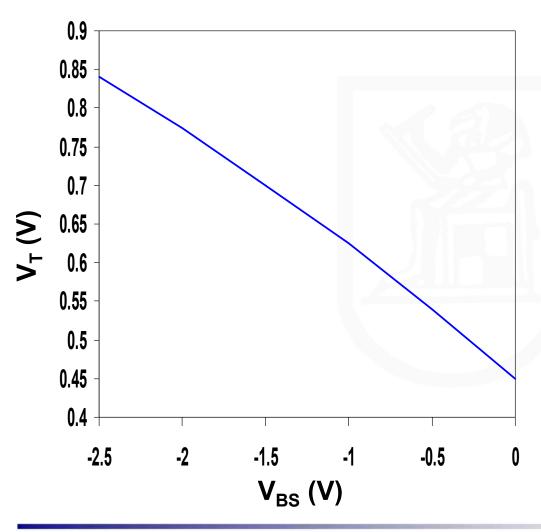
**V**<sub>SB</sub> is the source-bulk voltage

 $V_{T0}$  is the threshold voltage at  $V_{SB} = 0$  and is mostly a function of the manufacturing process

Difference in work-function between gate and substrate material, oxide thickness, Fermi voltage, charge of impurities trapped at the surface, dosage of implanted ions, etc.

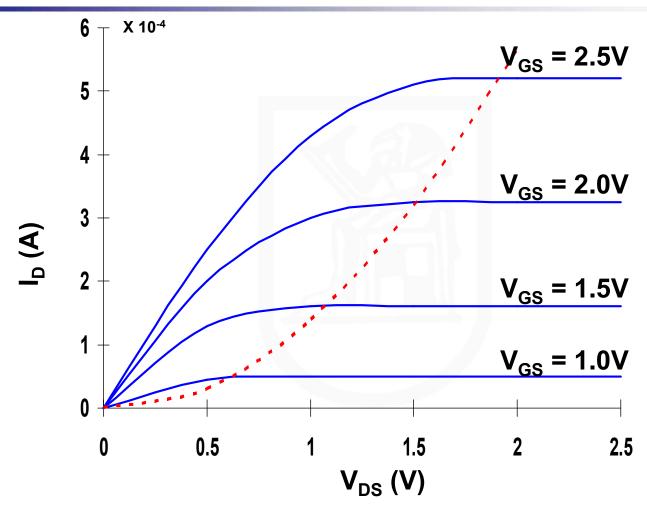
- $\phi_F = -\phi_T \ln(N_A/n_i)$  is the Fermi potential ( $\phi_T = kT/q = 26mV$  at 300K is the thermal voltage;  $N_A$  is the acceptor ion concentration;  $n_i \approx 1.5 \times 10^{10}$  cm<sup>-3</sup> at 300K is the intrinsic carrier concentration in pure silicon)
- $\gamma = \sqrt{(2q\epsilon_{si}N_A)}/C_{ox}$  is the body-effect coefficient (impact of changes in  $V_{SB}$ ) ( $\epsilon_{si}$ =1.053x10<sup>-10</sup>F/m is the permittivity of silicon;  $C_{ox} = \epsilon_{ox}/t_{ox}$  is the gate oxide capacitance with  $\epsilon_{ox}$ =3.5x10<sup>-11</sup>F/m)

#### **The Body Effect**



- □ V<sub>SB</sub> is the substrate bias voltage (normally positive for n-channel devices with the body tied to ground)
- A negative bias causes V<sub>T</sub> to increase from 0.45V to 0.85V

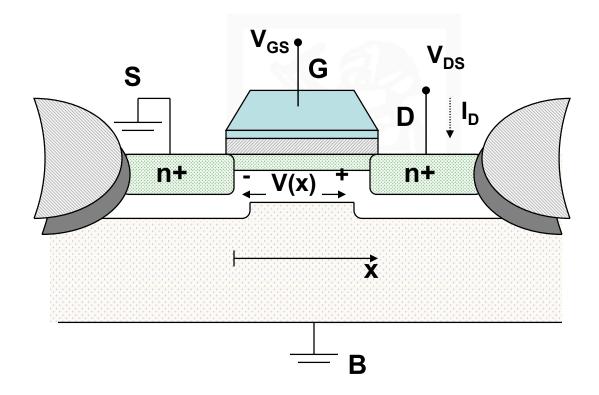
## **Long Channel I-V Plot (NMOS)**



NMOS transistor, 0.25um,  $L_d = 10um$ , W/L = 1.5,  $V_{DD} = 2.5V$ ,  $V_T = 0.43V$ 

#### **Transistor in Linear Mode**

#### Assuming $V_{GS} > V_{T}$



The current is a linear function of both  $V_{\text{GS}}$  and  $V_{\text{DS}}$ 

## Voltage-Current Relation: Linear Mode

For long-channel devices (L > 0.25 micron)

• When  $V_{DS} \le V_{GS} - V_{T}$ 

$$I_D = k'_n W/L [(V_{GS} - V_T)V_{DS} - V_{DS}^2/2]$$

where

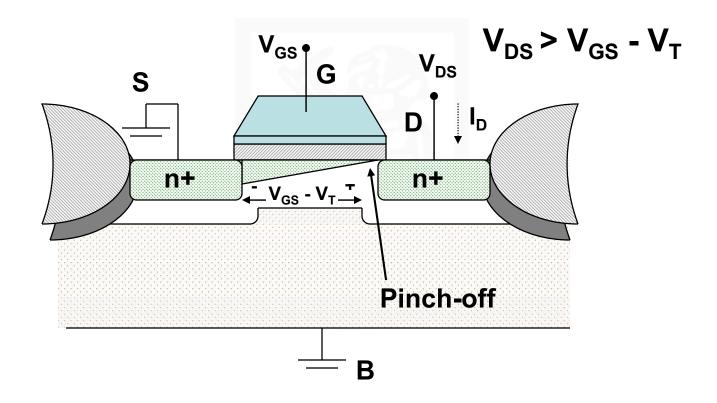
 $k'_n = \mu_n C_{ox} = \mu_n \varepsilon_{ox} / t_{ox} = is$  the process transconductance parameter ( $\mu_n$  is the carrier mobility (m²/Vsec))

 $k_n = k'_n$  W/L is the gain factor of the device

For small  $V_{DS}$ , there is a linear dependence between  $V_{DS}$  and  $I_{D}$ , hence the name resistive or linear region

#### **Transistor in Saturation Mode**

#### Assuming $V_{GS} > V_{T}$



The current remains constant (transistor saturates)

## Voltage-Current Relation: Saturation Mode

For long channel devices

• When  $V_{DS} \ge V_{GS} - V_{T}$ 

$$I_{D}' = k'_{n}/2 W/L [(V_{GS} - V_{T})^{2}]$$

since the voltage difference over the induced channel (from the pinch-off point to the source) remains fixed at  $V_{GS} - V_{T}$ 

 However, the effective length of the conductive channel is modulated by the applied V<sub>DS</sub>, so

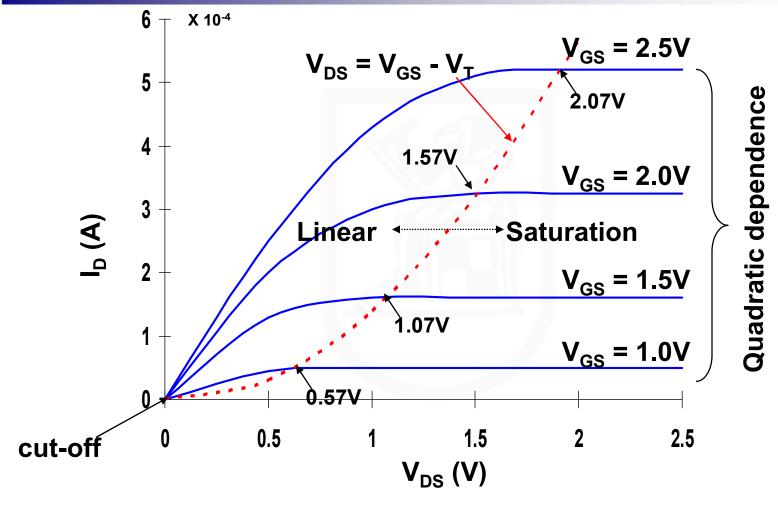
$$I_D = I_D' (1 + \lambda V_{DS})$$

where  $\lambda$  is the channel-length modulation (varies with the inverse of the channel length)

#### **Current Determinates**

- For a fixed V<sub>DS</sub> and V<sub>GS</sub> (> V<sub>T</sub>), I<sub>DS</sub> is a function of
  - the distance between the source and drain L
  - the channel width W
  - the threshold voltage V<sub>T</sub>
  - the thickness of the SiO<sub>2</sub> t<sub>ox</sub>
  - the dielectric of the gate insulator (e.g.,  $SiO_2$ )  $\varepsilon_{ox}$
  - the carrier mobility
    - for n-fets:  $\mu_n = 500 \text{ cm}^2/\text{V-sec}$
    - for p-fets:  $\mu_p = 180 \text{ cm}^2/\text{V-sec}$

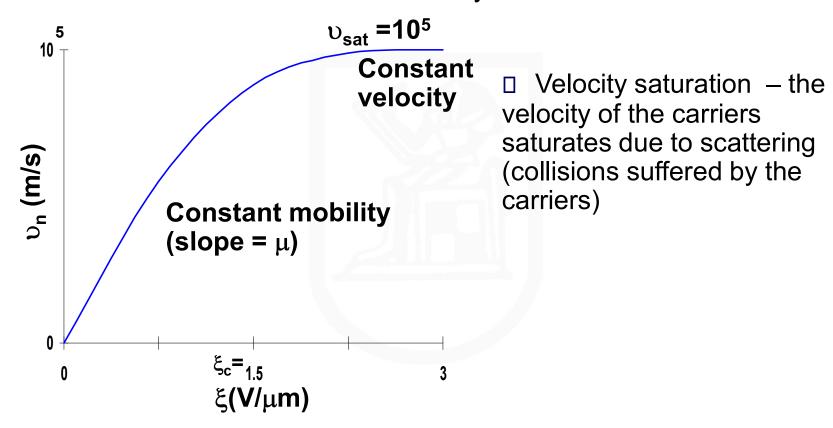
## **Long Channel I-V Plot (NMOS)**



NMOS transistor, 0.25um,  $L_d = 10um$ , W/L = 1.5,  $V_{DD} = 2.5V$ ,  $V_T = 0.43V$ 

#### **Short Channel Effects**

Behavior of short channel device mainly due to



For an NMOS device with L of  $0.25\mu m$ , only a couple of volts difference between D and S are needed to reach velocity saturation

## Voltage-Current Relation: Velocity Saturation

For short channel devices

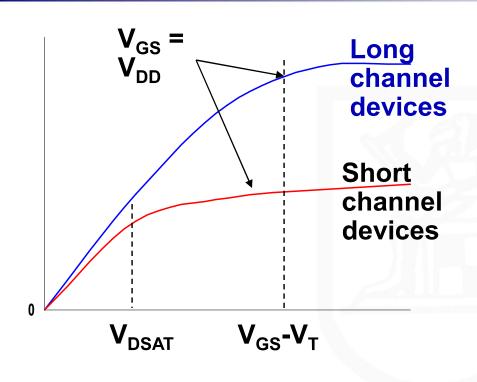
• Linear: When  $V_{DS} \le V_{GS} - V_T$   $I_D = \kappa(V_{DS}) k'_n W/L [(V_{GS} - V_T)V_{DS} - V_{DS}^2/2]$ 

where  $\kappa(V) = 1/(1 + (V/\xi_c L))$  is a measure of the degree of velocity saturation

• Saturation: When  $V_{DS} = V_{DSAT} \ge V_{GS} - V_{T}$  $I_{DSat} = \kappa (V_{DSAT}) k'_{n} W/L [(V_{GS} - V_{T})V_{DSAT} - V_{DSAT}^{2}/2]$ 

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#### **Velocity Saturation Effects**



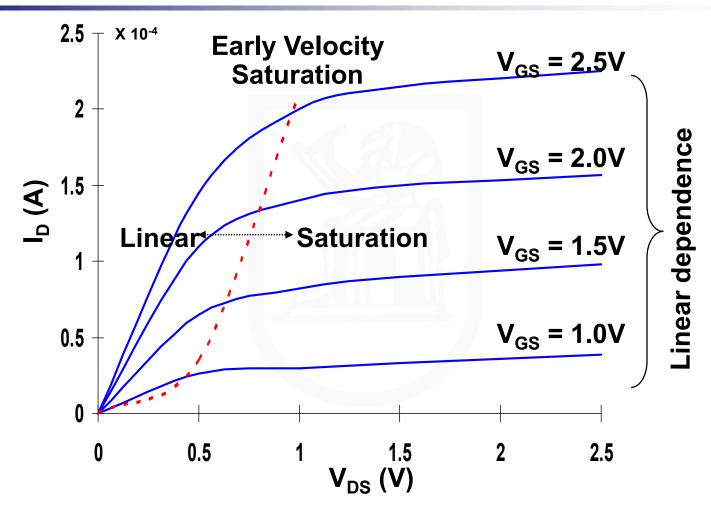
For short channel devices and large enough  $V_{GS} - V_{T}$ 

 $V_{DSAT} < V_{GS} - V_{T}$  so the device enters saturation before  $V_{DS}$  reaches  $V_{GS} - V_{T}$  and operates more often in saturation

□ I<sub>DSAT</sub> has a linear dependence w.r.t. V<sub>GS</sub> so a reduced amount of current is delivered for a given control voltage

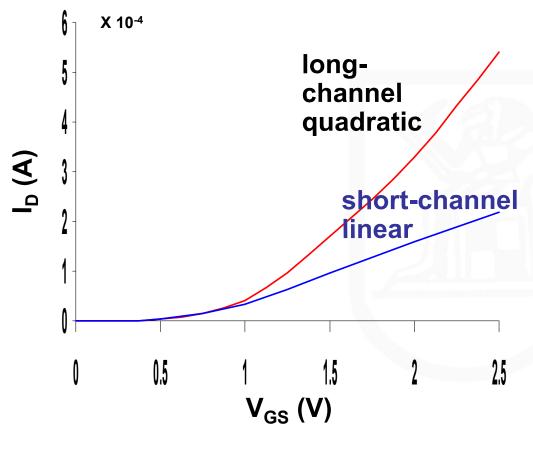
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### **Short Channel I-V Plot (NMOS)**



NMOS transistor, 0.25um,  $L_d = 0.25um$ , W/L = 1.5,  $V_{DD} = 2.5V$ ,  $V_T = 0.43V$ 

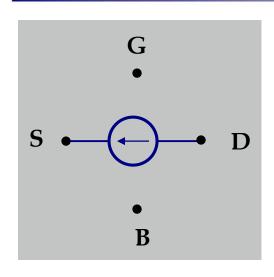
## **MOS I<sub>D</sub>-V<sub>GS</sub> Characteristics**



(for  $V_{DS} = 2.5V$ , W/L = 1.5)

- Linear (short-channel)
   versus quadratic (long-channel) dependence
   of I<sub>D</sub> on V<sub>GS</sub> in
   saturation
- Velocity-saturation causes the shortchannel device to saturate at substantially smaller values of V<sub>DS</sub> resulting in a substantial drop in current drive

#### The MOS Current-Source Model



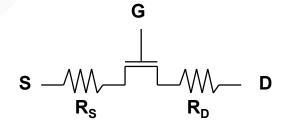
$$\begin{split} \textbf{I}_{D} &= 0 \qquad \text{for } \textbf{V}_{GS} - \textbf{V}_{T} < 0 \\ \textbf{I}_{D} &= \textbf{k'} \ \textbf{W/L} \ [(\textbf{V}_{GS} - \textbf{V}_{T}) \textbf{V}_{min} - \textbf{V}_{min}^{2} / 2] (1 + \lambda \textbf{V}_{DS}) \\ &\qquad \qquad \text{for } \textbf{V}_{GS} - \textbf{V}_{T} \geq 0 \\ &\qquad \qquad \text{with } \textbf{V}_{min} = \min(\textbf{V}_{GS} - \textbf{V}_{T}, \ \textbf{V}_{DS}, \ \textbf{V}_{DSAT}) \\ &\qquad \qquad \text{and } \textbf{V}_{GT} = \textbf{V}_{GS} - \textbf{V}_{T} \end{split}$$

Determined by the voltages at the four terminals and a set of five device parameters

	$V_{T0}(V)$	$\gamma(V^{0.5})$	$V_{DSAT}(V)$	k'(A/V <sup>2</sup> )	λ(V <sup>-1</sup> )
NMOS	0.43	0.4	0.63	115 x 10 <sup>-6</sup>	0.06
PMOS	-0.4	-0.4	-1	-30 x 10 <sup>-6</sup>	-0.1

## Other (Submicon) MOS Transistor Concerns

- Velocity saturation
- Sub-threshold conduction (aka weak inversion)
  - Transistor is already partially conducting for voltages below V<sub>T</sub>
- Threshold variations
  - In long-channel devices, the threshold is a function of the length (for low V<sub>DS</sub>)
  - In short-channel devices, there is a drain-induced threshold barrier lowering (DIBL) at the upper end of the V<sub>DS</sub> range (for small L)
- Parasitic resistances
  - resistances associated with the source and drain contacts



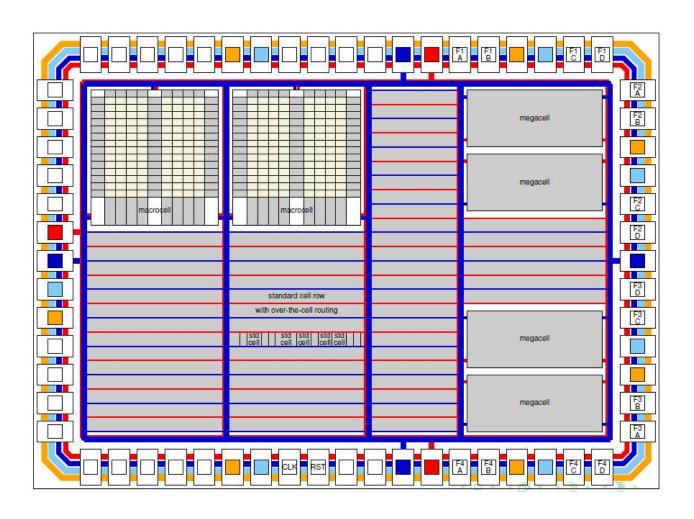
Latch-up

## **IC Design Flows**

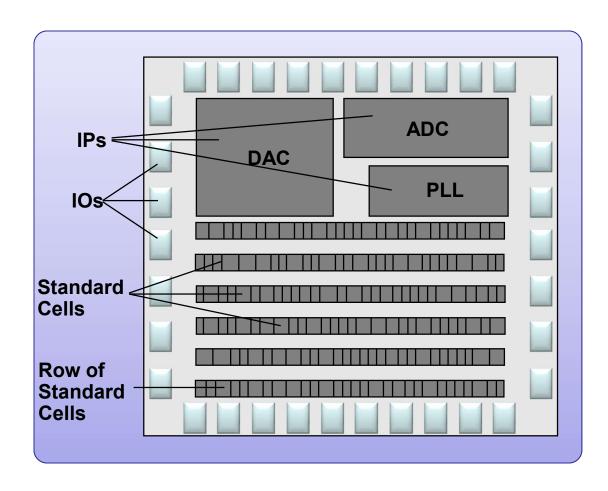


- The MOS Transistor
- Analog and Circuit Design
- Digital Logic Families
- Productivity Gap
- Digital Design Flows

## **Typical Chip Design**

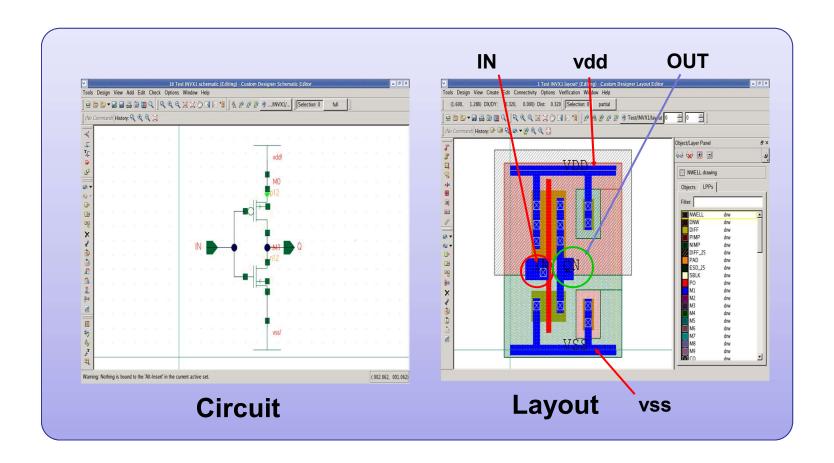


#### **IC Component Types**



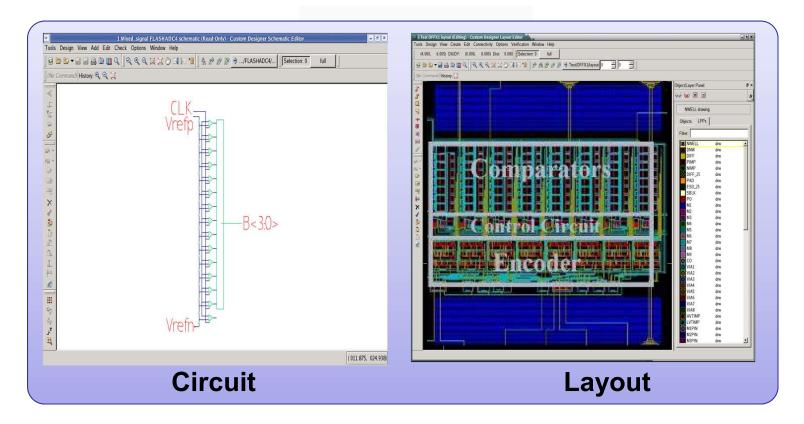
- Intellectual
   Property (IP)
   represents large
   blocks performing
   completed
   functions (DAC,
   ADC, PLL, etc)
- Standard Cells represent digital nodes performing simplest functions.

## **Circuit and Layout Editors**

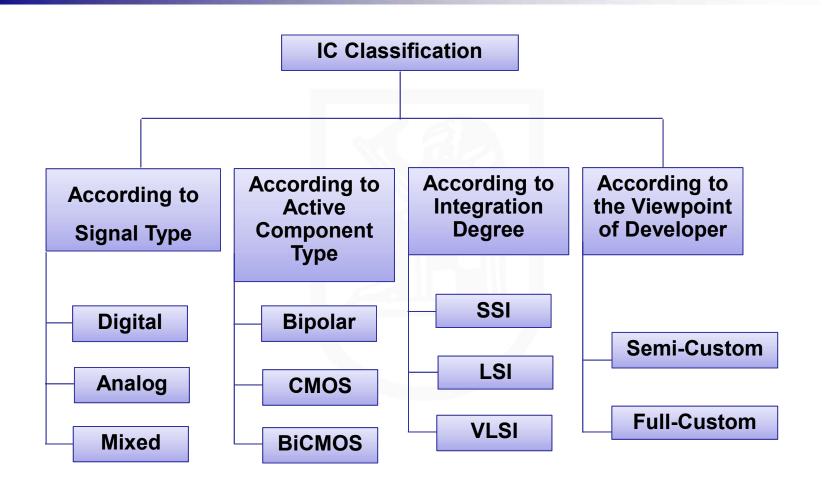


## **Custom Design Example**

#### **FLASHADC4**



#### **IC Classification**



# IC Classification: Signal Type

Analog

Combination of the first two

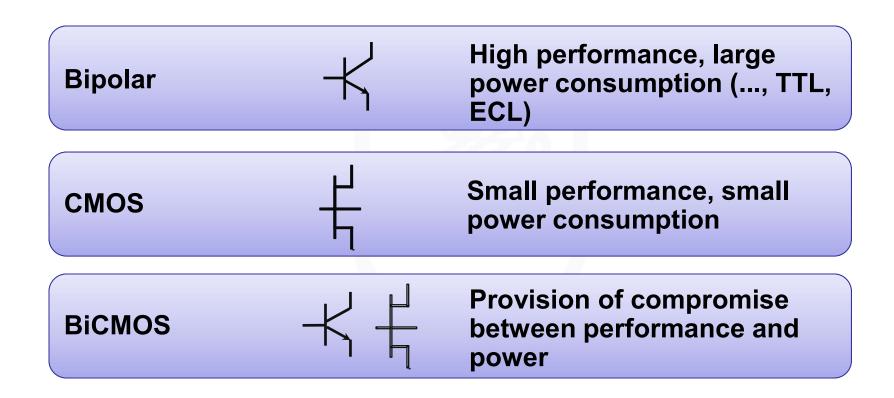
Electrical levels move up and down continuously

Electrical levels are either ON ("1) or OFF

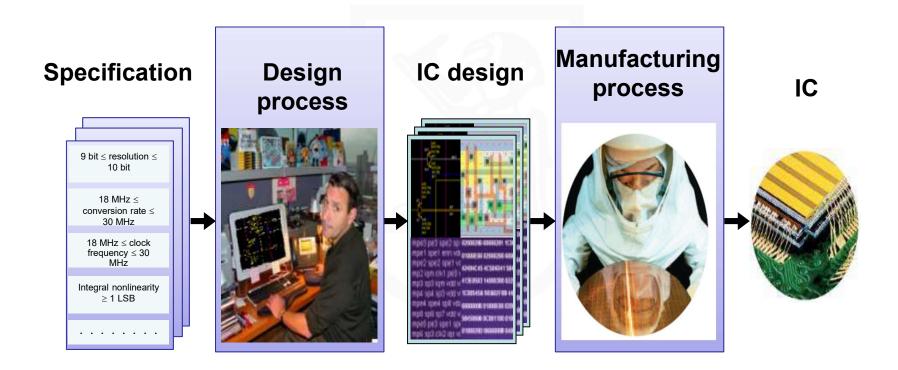
("0")

Combination of the first two

# IC Classification: Active Component Type



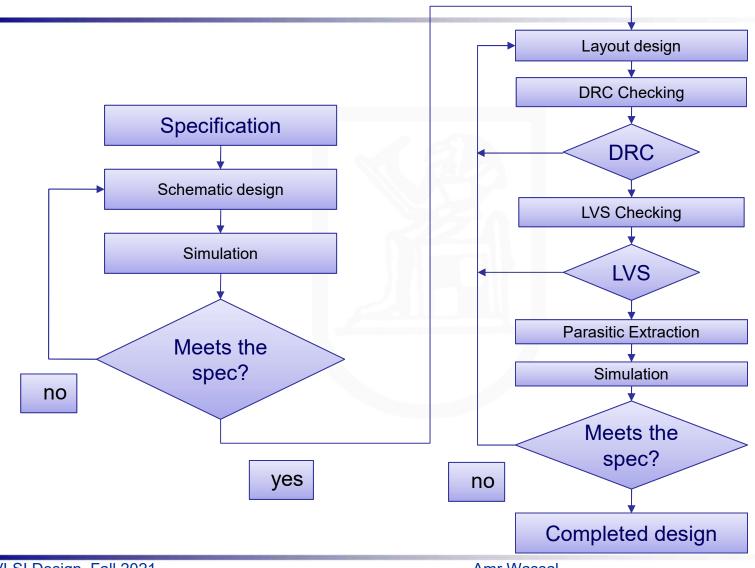
## **Phases of IC Design**



## **Analog Specification Example**

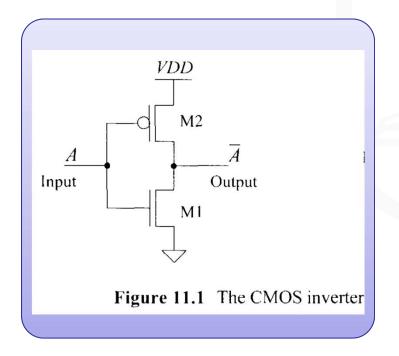
	Parameter description			Max		
1.	Process	3.3V IO devices in TSMC 0.11				
2.	Resolution	9		10	Bits	
3.	Conversion Rate	18		30	MHz	
4.	Input Clock Frequency	18		30	MHz	
5.	Integral Nonlinearity			1	LSB	
6.	Differential Nonlinearity			0.5	LSB	
7.	Gain Error		5		%FSR	
8.	Offset error		5		%FSR	
9.	Signal to Noise Ratio	56		62	DBc	
10.	Harmonic Distortion		-60		DBc	
11.	Temperature Drift			12	ppm/C	
12.	Reference Voltage		1.25		V	
13.	Analog Input Voltage		1.6		V	
14.	Power Supply Voltage1	1.08	1.2	1.32	V	
15.	Power Supply Voltage2	3	3.3	3.6	V	
16.	Power Dissipation		125	180	mW	
17.	Operating Temperature	0		125	°C	
18.	Spurious Free Dynamic Range			-10	dB	
19.	Effective Resolution Band Width		6		MHz	
20.	Clock jitter			28	Ps	

## **Analog/Circuit Design Flow**

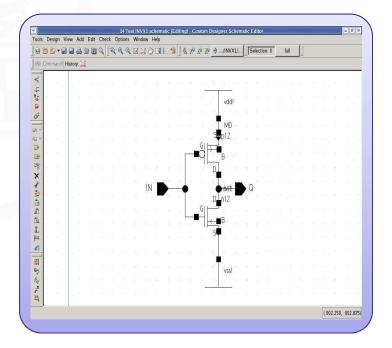


#### **Circuit Selection**

- Usually a known circuit structure is selected.
- Design can find a convenient structure which is known to be good for the problem being solved.

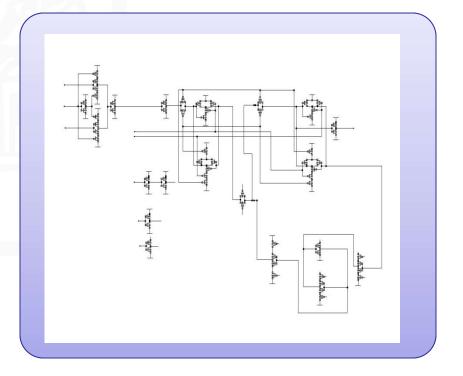






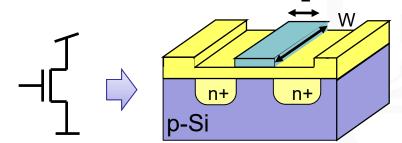
# **Circuit Design**

- All detailed circuits of designed IC are being developed usually at the transistor level.
- The aim of schematic design is to create a circuit which works at operating conditions defined in specification and have the parameter values needed.
- Schematic design
  - Structural synthesis
  - Parametric synthesis
  - Parametric optimization

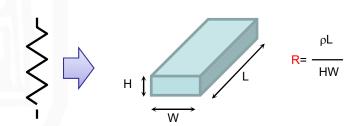


# **Parametric Optimization**

- Each device has configurable parameters
- Schematic designer changes these parameters to get a circuit which meets the spec
- Iterations of changes and spice simulations are used to tune these parameters ,



W - gate width, L - gate length

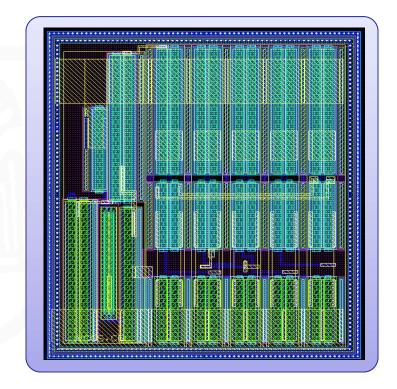


W - resistor width, L - resistor length

Transistor gate width and length, or resistor dimensions can be changed to change their electrical characteristics.

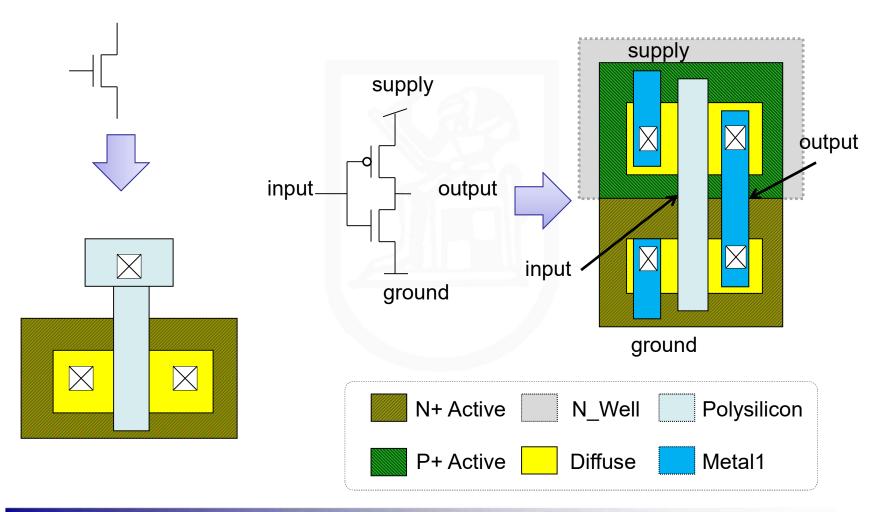
# **Physical Design (Layout)**

- The construction of the IC or its separate parts is being developed, i.e., geometrical sizes of separate elements, the material, etc.
- Place devices present in schematic and connect to each other according to schematic.
- Do necessary actions to ensure that Layout will not affect circuit operation and does not violate fabrication rules.

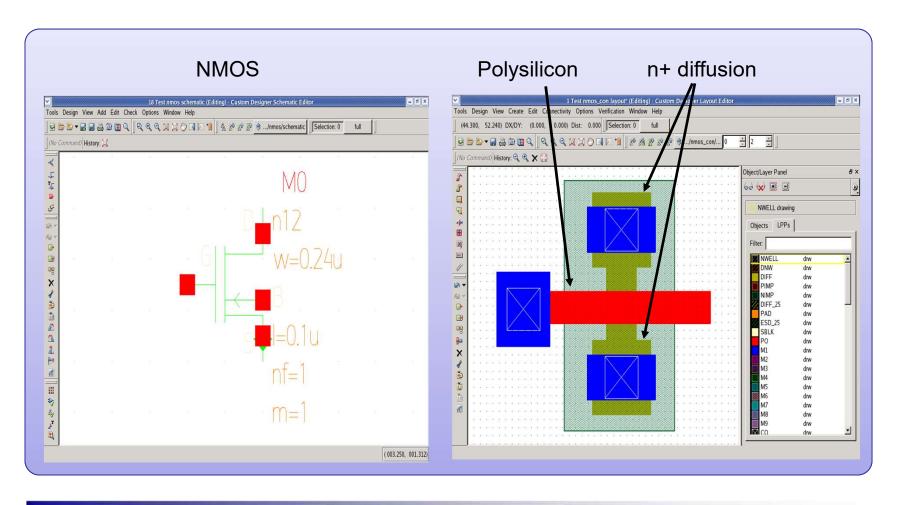


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# **Physical Design (Layout)**

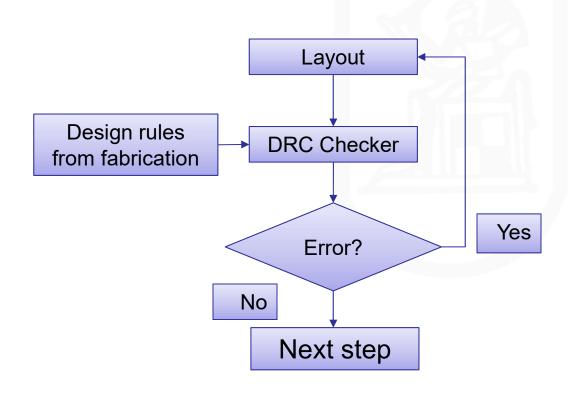


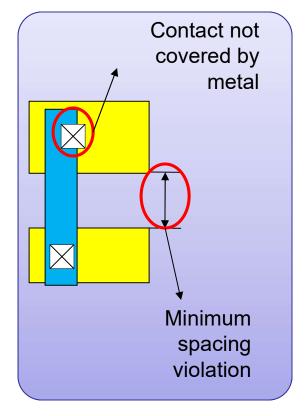
# **Physical Design (Layout)**



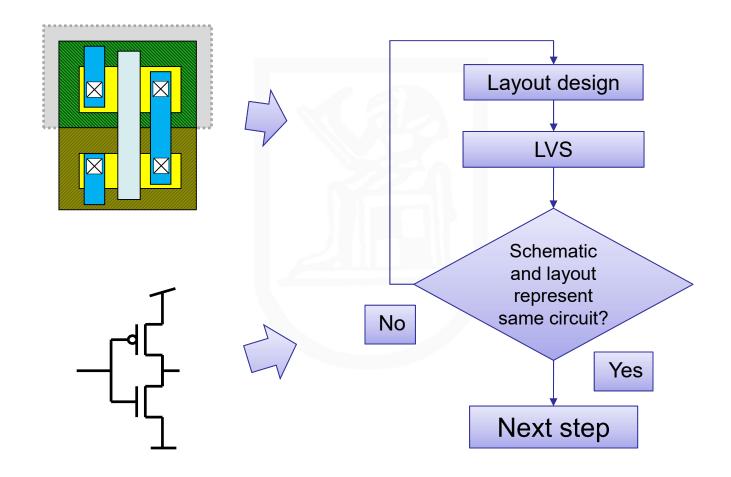
# Design Rule Check (DRC)

To ensure that Layout does not violate design rules there is a program that can check this



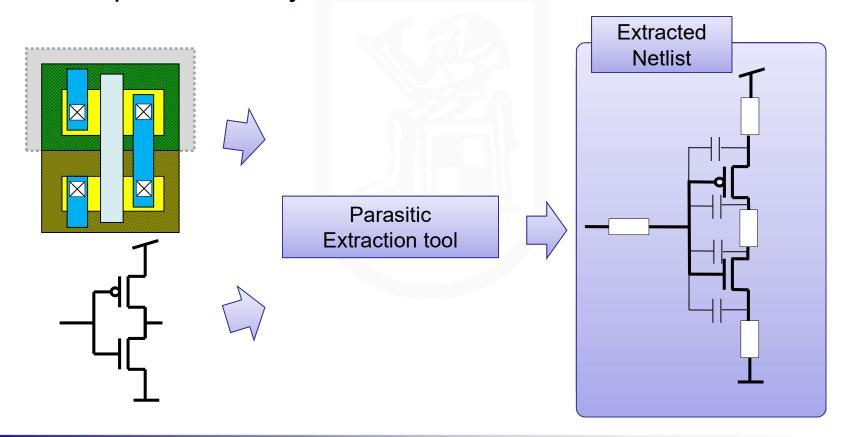


# **Layout Versus Schematic (LVS)**



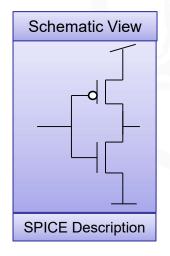
# **Layout Parasitic Extraction (LPE)**

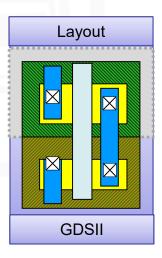
There is a parasitic extractor tool which calculates parasitic devices present in layout adds them back to circuit



#### **Deliverables**

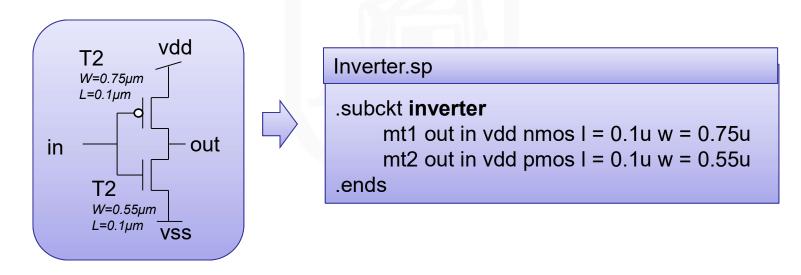
- Completed design is a set of files which represent different design views:
  - SPICE netlist format is used to deliver schematic view
  - GDSII binary format is used to deliver layout of the circuit





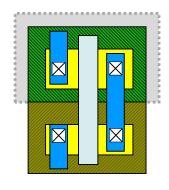
# **SPICE Description Example**

- SPICE is a hardware description language (HDL) which enables to describe circuit at device level
- It has text-based format that is readable and can be easily modified



#### An Example of GDSII File

#### GDSII is binary format, therefore it is not readable





#### Inverter.gds

# **Test Chip and its Testing**

- Samples of designed ICs in a small amount are being prepared.
- With the help of laboratory equipment different input signals are applied to manufactured ICs and the parameters relevant to the specifications are measured.
- In case of meeting all the requirements of the latter, IC largescale fabrication starts.
- Otherwise, compared with the spec's requirements, the earlier phases of design are carried out to exclude the present incompatibility or problem.

